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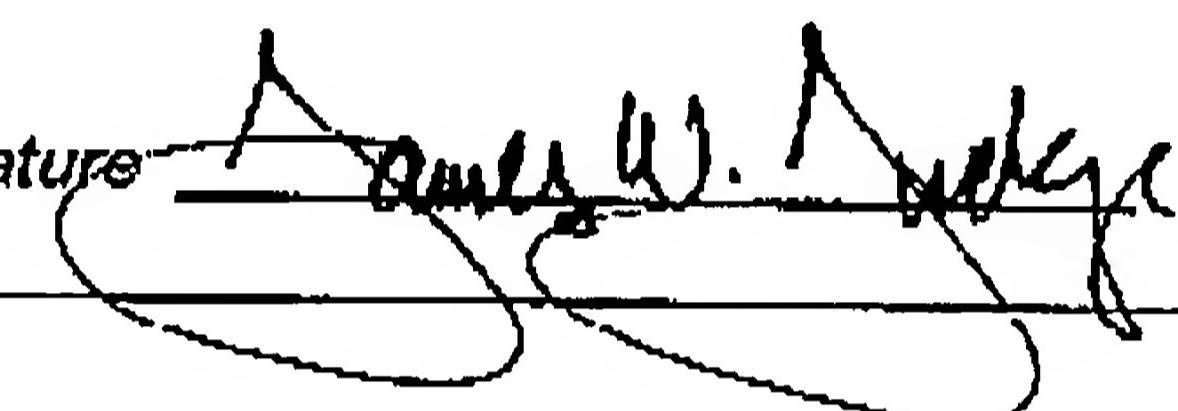
IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

App. No.	:	10/065,552	Confirmation No. 7687
Applicant	:	Shigeru Sawada	
Filed	:	October 29, 2002	
Tech. Cntr./Art Unit	:	2814	
Examiner	:	Louie Wai Sing	
Docket No.	:	39.002-AG	
Customer No.	:	29453	

I hereby certify that this correspondence is
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U.S. Patent and Trademark Office,
fax no. (703) 872-9306 on Sept. 20, 2004.

James W. Judge
Reg. No. 42,701

Signature



Honorable Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313 1450

REPLY Under 37 C.F.R. § 1.111

Sir:

In response to the Office action of August 18, 2004 Applicant hereby provisionally elects, with traverse, Group I.

REMARKS

On the grounds that the subject matter of claims 8-13, which depend from method claims 1-6 respectively, is inseparably dependent on the subject matter of claims 1-6, Applicant respectfully traverses the holding that claims 8-13 are drawn to a distinct invention.

Claims 8-13 are directed to compound semiconductor wafers having the novel property of being usable as-is despite having had their carrier concentrations profiled. The Office action quotes MPEP § 806.05(f) as stating that a process of making and the product made are patentably distinct if it can be shown that "the product as claimed can be made by another and materially different process." (Emphasis is the MPEP's.)

Although in the Office action it is suggested that "instead of using a C/V technique to profile the compound semiconductor wafer, it would be possible to use an electron beam to profile the compound semiconductor wafer," the Office action has not expressly set forth how such a substitution would produce the product as